Improvement of the thermal field to reduce edge dislocation of cast monocrystalline silicon

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Fig. 3 Simulation comparison diagram of temperature distribution below DS block before (a) and after (b) improvement (Unit: K)

Fig. 1. Schematic diagram of thermal field after improvement.

> Experimental Condition



> Improvement effect of silicon ingot after thermal field optimization





Fig. 4. PL test images of the crystal before (a) and after (b) the optimization of thermal field.

• The edge defects of silicon ingot are obviously improved

Fig. 2. Loading diagram of experimental silicon ingot

after thermal field optimization.

Conclusions

1. A carbon baffle felt is added under the graphite DS block to optimize the bottom heat dissipation at the initial stage of crystal growth.

2. The central temperature under the DS block increases, which will affect the solid-liquid interface at the initial stage of crystal growth and reduce the edge defects.